
Surface chemical analysis — Sputter depth profiling — Optimization using layered systems as reference materials

*Analyse chimique des surfaces — Profilage d'épaisseur par
bombardement — Optimisation à l'aide de systèmes mono- ou
multicouches comme matériaux de référence*





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ISO copyright office
Ch. de Blandonnet 8 • CP 401
CH-1214 Vernier, Geneva, Switzerland
Tel. +41 22 749 01 11
Fax +41 22 749 09 47
copyright@iso.org
www.iso.org